

IPR2017-00279, -00280, -00281, -00282
U.S. Patent No. RE40,264

Intel Petitioners' Demonstratives

March 7, 2018

Obviousness Combinations

Petition	
-279	<ul style="list-style-type: none">• Muller, Matsumura, Anderson and Hinman render independent claim 13 obvious (as does the Kadomura combination)• Adding Kikuchi renders claim 17 obvious• Adding Wright renders claims 19-20 obvious
-280 -281	<ul style="list-style-type: none">• Kadomura and Matsumura render independent claims 27, 37 and 51 obvious• Kikuchi and Matsumura also render those claims obvious
-282	<ul style="list-style-type: none">• Patent owner failed to address Muller, Matsumura and Wang, which render independent claims 56 and 60 obvious• Adding Kikuchi renders claim 63 obvious
All	<ul style="list-style-type: none">• Most dependent claims are not separately contested

Temperature change and preselected time limitations

(19) United States
(12) Reissued Patent
Flamm



(10) Patent Number: US RE40,264 E
(45) Date of Reissued Patent: Apr. 29, 2008

13. wherein the thermal mass of the substrate holder is selected for a predetermined temperature change within a specific interval of time during processing; the

(64) Patent No. 6,231,776
Issued: May 15, 2001

6,042,991 A 3/2000 Denison et al 427,579
6,048,798 A 4/2000 Gadgil et al 438,714
6,068,784 A 5/2000 Collins et al 716,628

27. wherein substrate temperature is changed from the selected first substrate temperature to the selected second substrate temperature, using a measured substrate temperature, within a preselected time interval for processing, and at least the first substrate temperature or the second substrate temperature, in single or in combination, is above room temperature.

37. wherein the substrate holder is heated above room temperature during at least one of the first or the second film treatments, and the substrate temperature control circuit is operable to change the substrate temperature from the selected first substrate temperature to the selected second substrate temperature within a preselected time period to process the film.

51. the substrate temperature control circuit effectuates the change from the first substrate temperature to the second substrate temperature within a preselected time period.

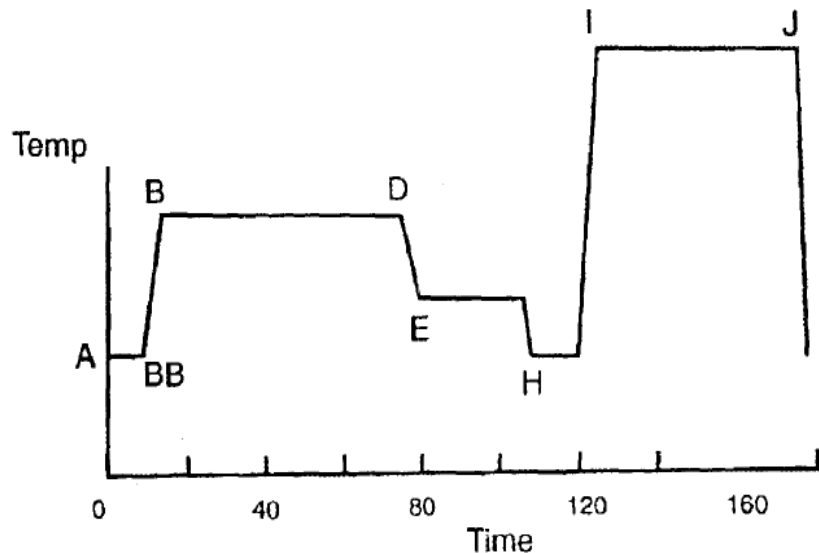
56. wherein the substrate holder is heated to a temperature operable to maintain at least one of the selected first and the selected second substrate temperatures above 49° C., and the substrate temperature is changed from the first substrate temperature to the second substrate temperature with a control circuit operable to effectuate the changing within a preselected time period that is less than the overall process time associated with the etching the first silicon-containing layer and the second silicon-containing layer.

60. wherein the first substrate temperature is different from the second substrate temperature and the first substrate temperature is changed to the second substrate temperature with a substrate temperature control circuit within a preselected time to etch the silicide layer.

'264 patent (Ex. 1001), claims 13, 27, 37, 51, 56, 60

Intel Corp. et al. Exhibit 1001

Matsumura, like the '264 patent, relies on temperature changes in a preselected time period



'264 patent (Ex. 1001), Fig. 10

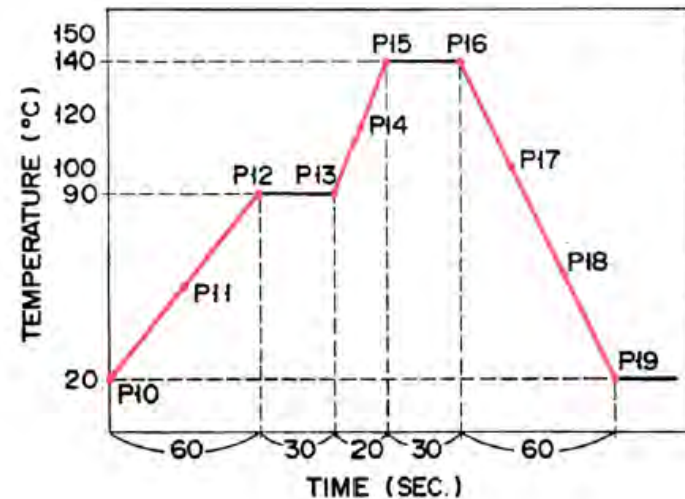


FIG. 9

(I) A recipe shown in FIG. 9 is inputted into the PID controller 203 by the keyboard 20a. Points P10 to P19 are set in the recipe so as to surely reproduce the thermal history curve of the wafer W. Information relating to temperatures and times at these points P10 to P19 is inputted as a command temperature table to the CPU 201. In the case of this recipe, the heating speed at a first

Matsumura (Ex. 1003), Fig. 9, 8:56-62

Matsumura, like the '264 patent, relies on temperature changes in a preselected time period

Still further, the present invention has been applied to the adhesion and baking processes for semiconductor wafers in the above-described embodiments, but it can also be applied to any of the ion implantation, CVD, etching and ashing processes.

The object of the present invention is therefore to provide a simpler method of heat-processing semiconductor devices whereby temperatures of the semiconductor devices can be controlled at devices-heating and -cooling times so as to accurately control their thermal history curve.

Further, when the semiconductor devices of same kind are to be heated and cooled, their thermal history curve can be controlled accurately same at their heating and cooling times, thereby enhancing their reliability. Particularly, their thermal history curve can be made accurately same. Therefore, no irregularity can be found in the property of their resists, and their qualities can be made same.

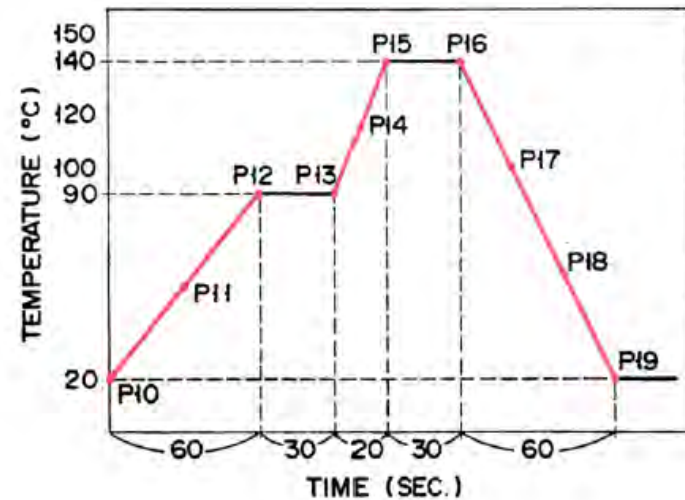


FIG. 9

Matsumura (Ex. 1003), Fig. 9, 10:3-7,
2:60-65, 10:22-29

Explore Litigation Insights

Docket Alarm provides insights to develop a more informed litigation strategy and the peace of mind of knowing you're on top of things.

Real-Time Litigation Alerts



Keep your litigation team up-to-date with **real-time alerts** and advanced team management tools built for the enterprise, all while greatly reducing PACER spend.

Our comprehensive service means we can handle Federal, State, and Administrative courts across the country.

Advanced Docket Research



With over 230 million records, Docket Alarm's cloud-native docket research platform finds what other services can't. Coverage includes Federal, State, plus PTAB, TTAB, ITC and NLRB decisions, all in one place.

Identify arguments that have been successful in the past with full text, pinpoint searching. Link to case law cited within any court document via Fastcase.

Analytics At Your Fingertips



Learn what happened the last time a particular judge, opposing counsel or company faced cases similar to yours.

Advanced out-of-the-box PTAB and TTAB analytics are always at your fingertips.

API

Docket Alarm offers a powerful API (application programming interface) to developers that want to integrate case filings into their apps.

LAW FIRMS

Build custom dashboards for your attorneys and clients with live data direct from the court.

Automate many repetitive legal tasks like conflict checks, document management, and marketing.

FINANCIAL INSTITUTIONS

Litigation and bankruptcy checks for companies and debtors.

E-DISCOVERY AND LEGAL VENDORS

Sync your system to PACER to automate legal marketing.